



# Star Systems

## Integrated Systems

	SL-200	SL-300	SL-450
Wafer Sizes	≤200mm†	≤300mm†	≤450mm†
Pay Load (Std/Hi Load)	1.5/5.0 kg*		
Mounting Facet	200mm MESC	300mm MESC	450mm MESC
Axes of Motion	R, Z		
Vacuum performance Base operating pressure Leak Rate	<5.00E-07 Torr 1.00E-09 scc He/sec		
Input Power	24 VDC 2.0 Amps		
Maximum Temperature	100°C		
Exposed Materials	6061-T6 Aluminum, Stainless Steel 300 and 400 Series, Viton, Borosilicate Glass, Crytox, Delrin, PEEK		
Control Interface	RS-232 / Ethernet		
MCBF	>3.00E+05		
CE	Compliant		
Repeatability R Z	0.15mm‡ 0.10mm‡		
Max. Reach	305mm**	355mm**	635mm**
Vertical Stroke	0.5°***		

† SEMI standard sizes available and custom end effectors available upon request.

‡ Measured as three standard deviations (3σ)

\* End effector design may impact max payload capability

\*\* Maximum reach measured from the edge of the slit valve

\*\*\* Vertical stroke is optional